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Client Reference: P-0362.010-US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of VAN BILSEN et al. Confirmation Number: 4408

Application No.: 10/665,404

Group Art Unit: 2878

Filed: September 22, 2003

Examiner: JOHN R. LEE

Title: ALIGNMENT SYSTEMS AND METHODS FOR LITHOGRAPHIC SYSTEMS

COMMENTS ON EXAMINER'S STATEMENT OF REASONS FOR ALLOWANCE

Mail Stop Issue Fee

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the Notice of Allowance dated March 13, 2007, consideration of the following comments is respectfully requested.

In the Notice of Allowability, the Examiner has set forth "Reasons for Allowance." The Applicants respectfully traverse these Reasons. Specifically, it is submitted that the subject matter of the allowed claims is patentable for their respective recitations of claimed combinations as a whole. That is, the patentability of the claims rests on the combination of recited elements and limitations. As such, Applicants submit that no one element or limitation in particular should be deemed to impart or be required for patentability of the claims. Furthermore, Applicants also submit that the dependent claims are allowable not only for their dependence on the allowed independent claims, but also for the additional subject matter recited in each of those dependent claims.

Respectfully submitted,

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